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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

N. Bojarczuk Jr., et al.

Serial No.: 10/059,422

Group Art Unit: 2814

Filed: January 31, 2002

Examiner: Theresa Doan

METHOD OF FORMING LATTICE-MATCHED STRUCTURE ON SILICON AND

STRUCTURE FORMED THEREBY

Honorable Assistant Commissioner of Patents P.O. Box 1450

703-761-2376

Alexandria, VA 22313-1450

AMENDMENT UNDER 37 C.F.R. §1.111

Sir:

In response to the Office Action dated March 31, 2003, please amend the aboveidentified application as follows:

IN THE CLAIMS:

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JUL 3 1 2003

Please cancel withdrawn claims 1-14 and 28-55 without prejudice or disclaimer. CENTER 2800

- 1-14 (Withdrawn and canceled)
- 15. (Original) A semiconductor structure, comprising:
 - a substrate:
 - a crystalline oxide layer formed over said substrate; and
 - an epitaxial silicon layer formed on said crystalline oxide layer.

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